

Device and Method for Processing Toxic Gasses in Vortex Reacting Chamber

Abstract of the Disclosure

This invention provides a device and a method for processing toxic gasses in a vortex reacting chamber, where gases entering the reacting chamber are introduced into the reacting chamber along a tangential direction, such that the forces generated by a velocity field caused by the gases may be used to clean the fine solid molecules attached to the reactor inner wall that the gasses subsequently pass through, for reducing accumulation of the fine solid molecules produced by toxic gasses during pyrolysis onto the reactor inner wall thereby postponing the periodical cleaning required by the reactor. In addition, this invention discloses an effective measure for processing the fine molecules washed off from the reacting chamber inner wall by dividing the subsequently water tank set into two functional sections, including a first water tank and second water tank, so as to effectively carry away all fine molecules suspended above the water level within the water tank set.